

FAST [Default.aspx] - [X] [X] [X]

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☒ 3RS:
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☐ L2: (459) ((secu\$6) near3 (element\$2 or device\$2 or corn
☐ L3: (0) 1 and 2
☐ L4: (110) ((support\$6) adj3 (element\$2 or component\$2 or
☐ L5: (0) 1 and 4
☐ L6: (4863) ((support\$6) adj3 (element\$2 or component\$2
☐ L7: (0) 1 and 6
☐ L1: (46) (microelectronic\$5 adj3 workpiece\$3) and (suppo
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(microelectronic\$5 adj3 workpiece\$3) and (support\$2) and (contact\$6 near3 surface\$2) and (movable or
 moveable)

A [115] cm A [153] cm [3] Image [6] Text [6] HTML

	U	Document ID	Issue Date	Pages	Title	Current OR	Current XRef	Retrieval Class	Inventor
1	<input type="checkbox"/>	US 6893555 B2	20050517	41	Apparatus and method for regulating fluid flows, such as flows of	118/508	137/467.5; 137/488		Peace, Steven L.
2	<input type="checkbox"/>	US 6878955 B2	20050412	19	Method and apparatus for accessing microelectronic workpiece containers	250/559.33	250/559.29; 414/933		Harris, Randy et al.
3	<input type="checkbox"/>	US 6869510 B2	20050322	42	Methods and apparatus for processing the surface of a microelectronic	204/297.01	204/297.09		Woodruff, Daniel J. et
4	<input type="checkbox"/>	US 6861027 B2	20050301	30	Method and apparatus for processing a microelectronic workpiece including an	266/256	118/725		Weaver, Robert A. et
5	<input type="checkbox"/>	US 6854473 B2	20050215	15	Method and apparatus for executing plural processes on a microelectronic	134/95.3	134/103.2; 134/198		Hanson, Kyle M. et al
6	<input type="checkbox"/>	US 6853141 B2	20050208	57	Capacitively coupled plasma reactor with magnetic plasma control	315/111.21	315/111.41; 315/111.51		Hoffman, Daniel J. et
7	<input type="checkbox"/>	US 6846519 B2	20050125	14	Method and apparatus for electroless deposition with temperature-controlled	427/430.1	427/437; 427/443.1		vanov, Igor C. et al.
8	<input type="checkbox"/>	US 6805778 B1	20041019	60	Contact assembly for supplying power to workpieces during electrochemical	204/297.1	204/266.1; 204/297.14		Balz, Jr., Robert W. et
9	<input type="checkbox"/>	US 6794291 B2	20040921	36	Reactor for processing a semiconductor wafer	436/694	118/715; 118/729		Peace, Steven L. et
10	<input type="checkbox"/>	US 6750374 B2	20040524	36	Method and apparatus for processing a microelectronic workpiece at an	266/252	215/444.1; 219/468.1		Weaver, Robert A. et
11	<input type="checkbox"/>	US 6773560 B2	20040510	20	Dry contact assemblies and plating machines with dry contact assemblies	204/224R			Pedersen, John M. et

☒ HTML

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